

wherein said temperature-measuring means is a thermoviewer.

Please add new claims 5 and 6 as follows:

5. (New) The ceramic heater for heating a semiconductor wafer according to claim

2,

wherein said temperature-measuring means is a temperature-measuring element.

6. (New) The ceramic heater for heating a semiconductor wafer according to claim

2,

wherein said temperature-measuring means is a thermoviewer.

IN THE ABSTRACT

Please cancel the original Abstract on page 37 in its entirety and insert therefor:

ABSTRACT

A ceramic heater to heat an object to be heated, such as a silicon wafer, evenly. The ceramic heater has a resistance heating element formed on the surface of the ceramic substrate or inside the ceramic substrate, and is equipped with a temperature-measuring device for measuring the temperature of the ceramic substrate and an object to be heated. A control unit supplies electric power to the heating element. A memory unit stores the temperature data measured by the temperature-measuring device. An operation unit calculates electric power required for the heating element from the measured temperature. The ceramic heater is further constituted such that the heating element is divided into at least 2 or more circuits and different electric power is supplied to each of the circuits of the resistance heating element.